

**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

Docket Number (Optional)  
**LEE.002**

Application Number  
**NEW**

Applicant(s)  
**Shone FUJA**

Filing Date  
**January 5, 2004**

Group Art Unit  
**To Be Assigned**

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
DV	A	5,739,567	04/14/1998	WONG			
	B	5,770,514	06/23/1998	MATSUDA et al.			
	C	6,544,824	04/08/2003	PRADEEP et al.			
DV	D	6,365,452	04/02/2002	PERNG et al.			

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

DV	E	R. Muralidhar et al., "A 6V Embedded 90nm Silicon Nanocrystal Nonvolatile Memory", DigitalDNA Laboratories and the embedded Memory Center, 2003 IEEE, 4 pgs.
DV	F	B. De Salvo et al., "How far will Silicon nanocrystals push the scaling limits of NVMs technologies?", 2003 IEEE, 4 pgs.

EXAMINER *Phuland*

DATE CONSIDERED *07/06/05*

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.